Icemos Technology Ltd Product Specification 1000.729901 Issue Date 13 December 2022 10

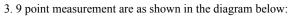
Part Number	Customer	

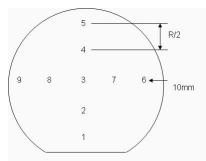
Category		Parameter	Specification	Measurement Method
OverallWafer	1.0	Diameter	150.00 +/- 0.50 mm	
	2.0	Primary Flat Orientation	{110} +/-1 degree	Customer supplied material
	3.0	Primary Flat Length	57.50 +/- 2.50 mm	Customer supplied material
	4.0	Secondary Flat Orientation	none	Customer supplied material
	5.0	Overall Thickness	631.00 +/- 11.00 μm	ADE, 100%
	6.0	Total Thickness Variation (TTV)	<3.00μm	Guaranteed by Process
	7.0	Bow	<60.00µm	ADE to ASTM F534, 100%
	8.0	Warp	<60.00μm	ADE to ASTM F534, 100%
	9.0	Edge Chips	0	Bright Light, 100%
	10.0	Edge Exclusion	5mm	
HandleSilicon	11.0	Handle Growth Method	CZ	Customer supplied material
	12.0	Handle Orientation	{100} +/- 0.5 degree	Customer supplied material
	13.0	Handle Thickness	600.00 +/- 10.00 μm	ADE, 100%
	14.0	Handle Doping Type	N	Customer supplied material
	15.0	Handle Dopant	Phosphorous	Customer supplied material
	16.0	Handle Resistivity	1~10 Ohmem	Customer supplied material
	17.0	Backside Finish	Polished with oxide and lasermark	Guaranteed by process
BuriedOxide	18.0	Oxide Type	Thermal	
	19.0	Oxide Thickness	10,000.00 +/- 500.00 A	Nanospec centre point, 4%
	20.0	Oxide formed on	Handle	
DeviceSilicon	21.0	Device Growth Method	CZ	Customer supplied material
	22.0	Device Orientation	{100} +/- 0.5 degree	Customer supplied material
	23.0	Nominal Thickness	30.00 +/- 0.50 μm	Filmetrics 9pts, 100% (note3)
	24.0	Distance to device silicon edge from wafer edge	< 2mm	Typical by Process
	25.0	Device Doping Type	N	Customer supplied material
	26.0	Device Dopant	Phosphorous	Customer supplied material
	27.0	Device Resistivity	1~10 Ohmcm	Customer supplied material
	28.0	Surface Voids	None	Bright Light, 100% (note2)
	29.0	Haze	None	Bright Light, 100% (note2)
	30.0	Scratches	none on the front-side	Bright Light, 100% (note2)

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Part Number		Customer		
Category	Parameter	Specification	Measurement Method	
Shipping Details	Wafer per box :	Max 25		
	Packaging:	Taped Polypropylene Wafer Box Empak, Ultrapak, 150.00mm Antistatic Double Bagging		
	Lot Shipment Data	Device Thickness Bow / Warp Data Handle and SOI Thickness		
Explanatory Notes	1. Microscope inspec	tion performed using microscope scan as below. 5x objective.		
	2. All bright light inspections performed exclude all wafer area outside the edge exclusion defined in Overall			

Wafer, Edge Exclusion. High intensity bright lamp inspection as per ASTM F523.





Additional Information